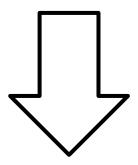


Project description

"Simulation and measurements of heavily irradiated silicon detectors: CMS HPK and HGC campaigns"



Expand TRACS functionality and performance



TRACS is an open source program developed by Pablo de Castro (Summer Student 2014)
Fast TRAnsit Current Simulator based on Ramo's theorem that uses external libraries for calculations FEM

Project description

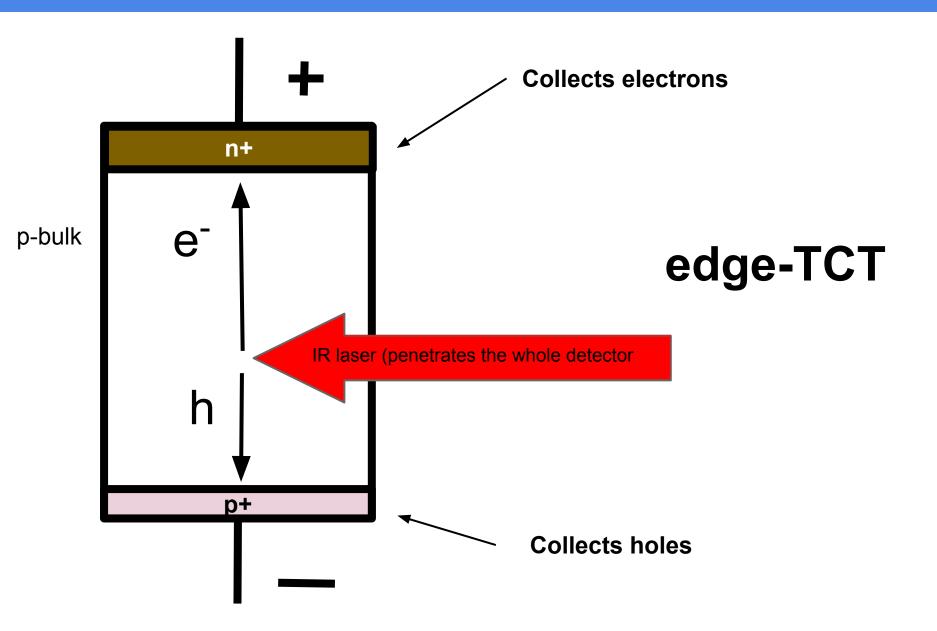
What we want to achieve:

"Fast simulation of irradiated detectors with selectable free parameters that can be fitted to measurements"

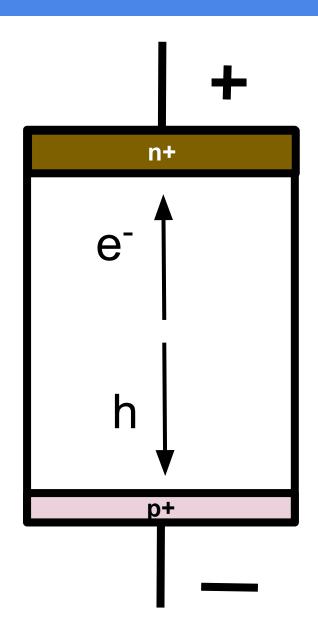
What we need to implement in TRACS

- Simulation of irradiated detectors
- Tunable Neff distribution —— Our free parameters
- Simulate trapping effects
- Accurate simulation of electronics (Shaping)
- Performance improvements (parallelization?)

Basics of silicon detectors



Basics of silicon detectors



Velocity is proportional to the electric field



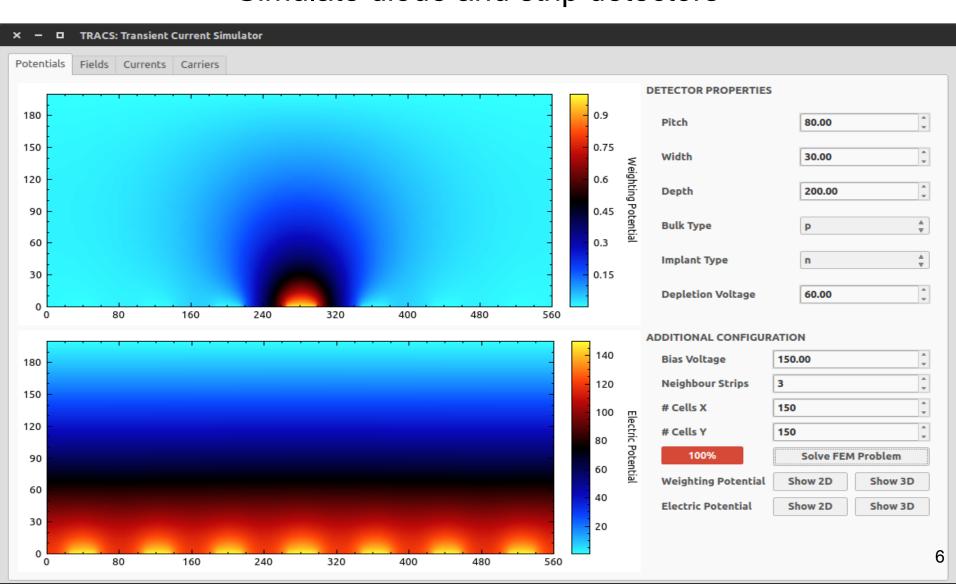
Current generated due to electric induction

i.e. its proportional to the velocity

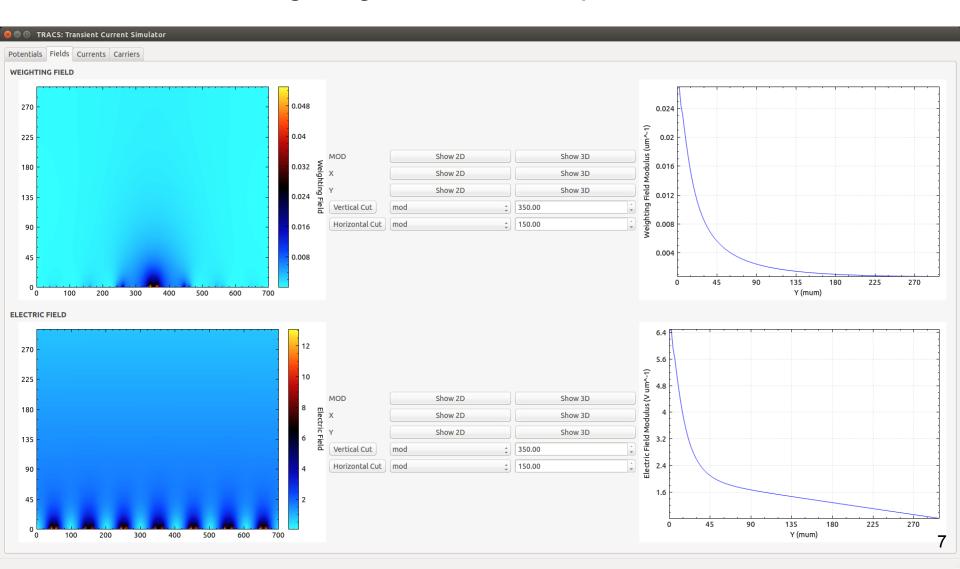


edge-TCT illumination allows as to "see" the field inside the detector

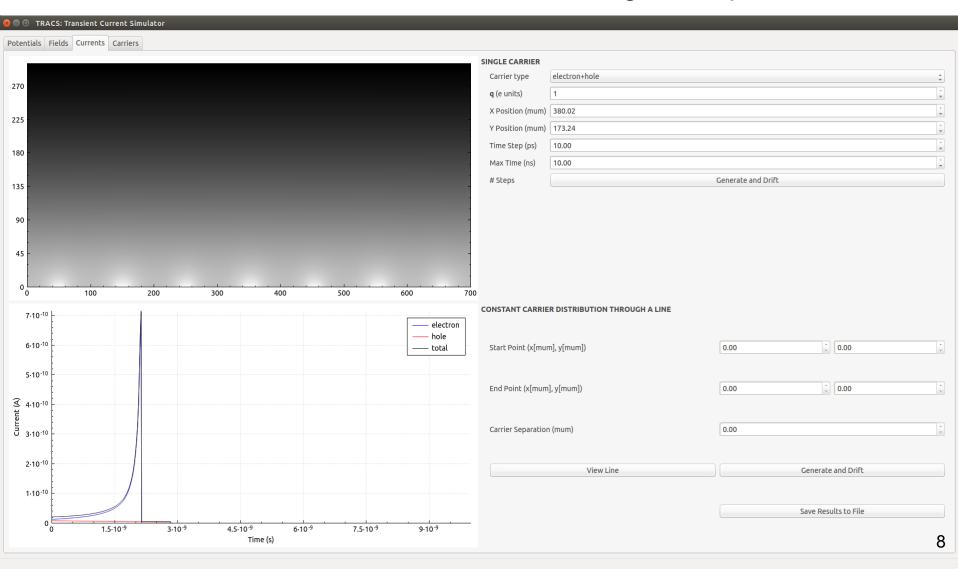
Simulate diode and strip detectors



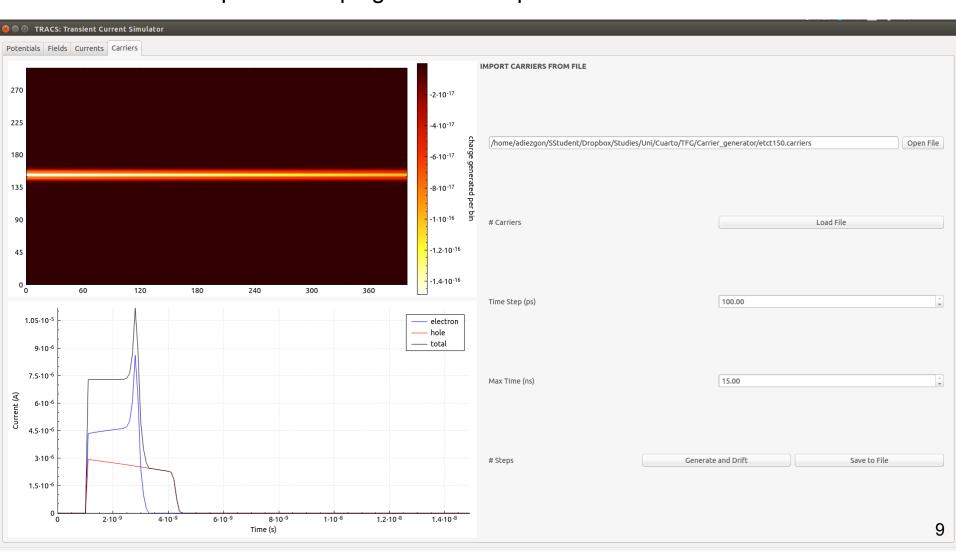
Calculate weighting and electrical potentials and fields



Simulate waveform due to a single e-h pair



Simulate signal generated by any kind of illumination simple RC shaping was also implemented in November



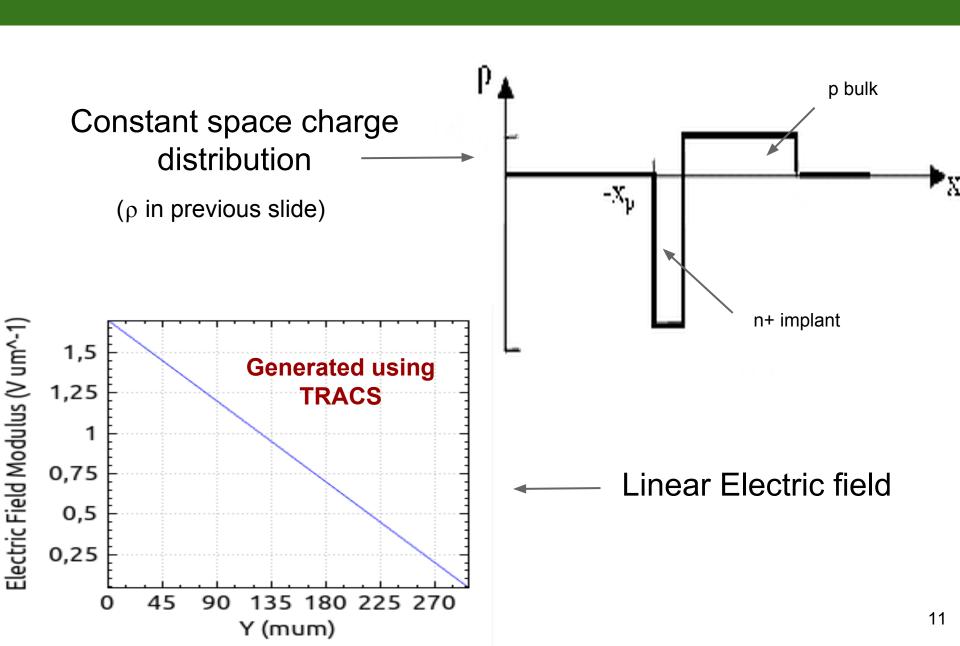
First Step - Changing Neff distribution

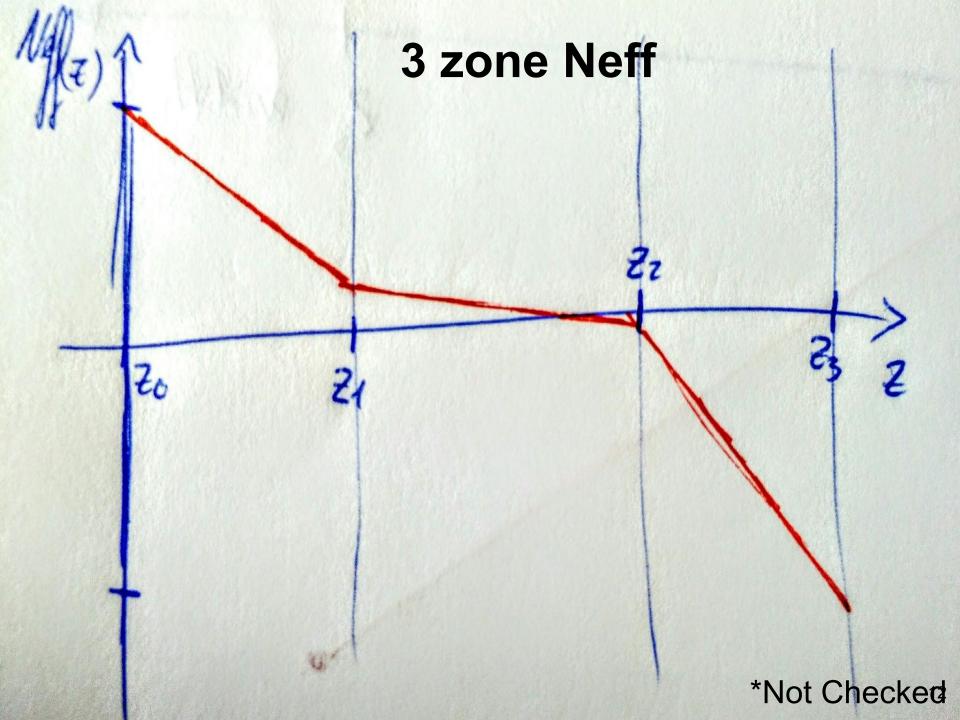
Why is Neff important?

$$\nabla E = \frac{\rho}{\varepsilon} \Longrightarrow \nabla \phi = \vec{E}$$

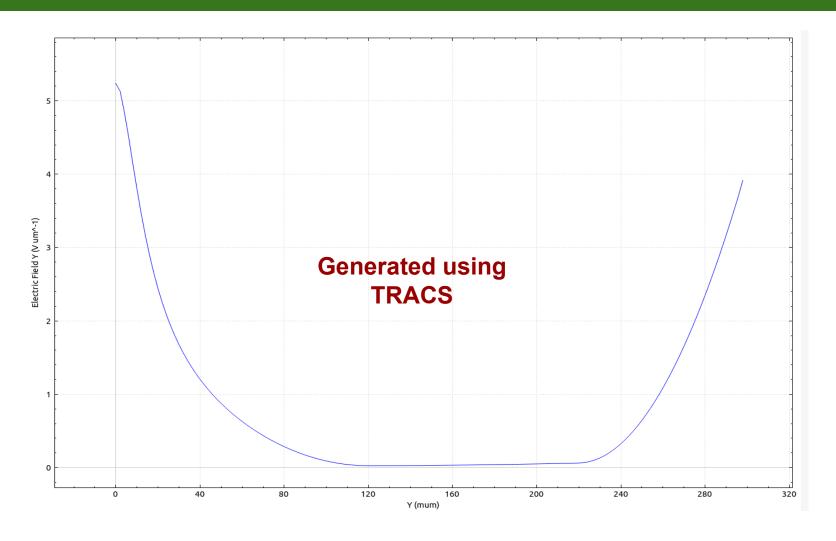
$$\nabla^2 \phi = \frac{\rho}{\varepsilon}$$
 Integrate once Get electric field Integrate twice Get electric potential

Neff before irradiation



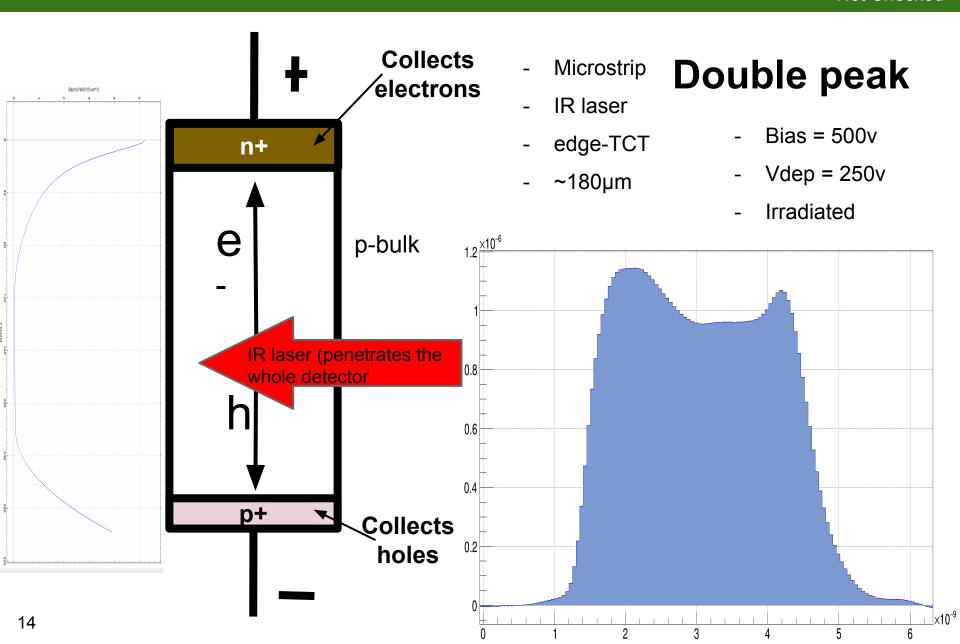


Third Approach* - 3 zone Neff



3 parabolas (one per Neff zone)

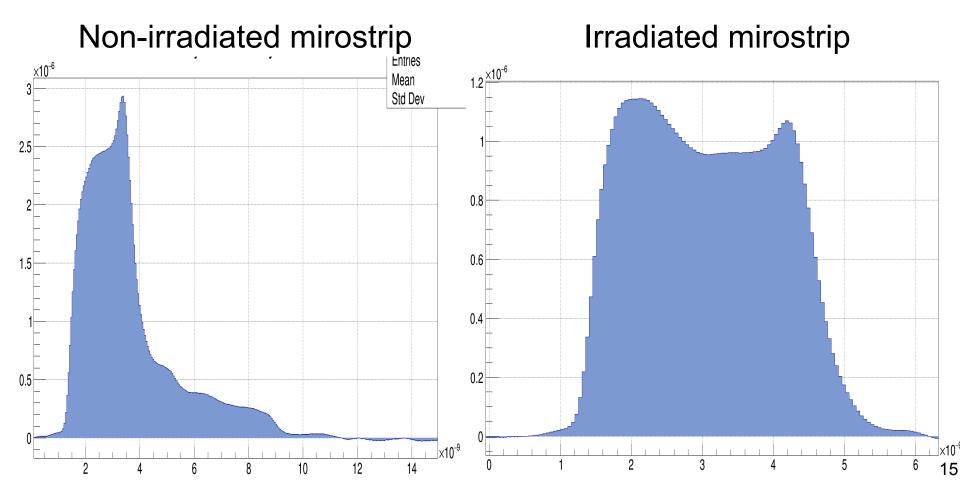
Second Approach* - 3 zone Neff



- Microstrip
- IR laser
- edge-TCT (~180µm)

- Bias = 500v
- $Vdep^* = 250v$

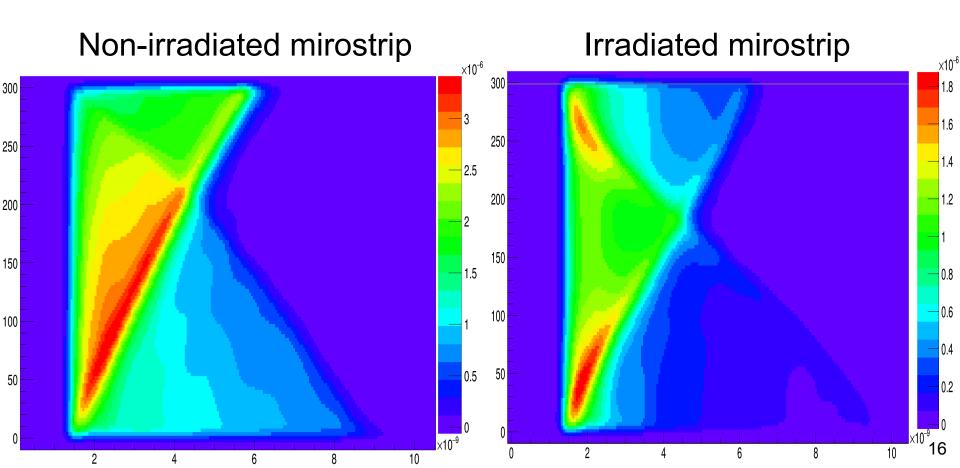
*Vdep has no relevance for irradiated simulations



- Microstrip
- IR laser
- edge-TCT

- Bias = 500v
- $Vdep^* = 250v$

*Vdep has no relevance for irradiated simulations



Progress report

All that TRACS already does and ...

- ✓ Simulation of irradiated detectors (given Neff distribution)
- ✓ Include trapping effects
- ☑ Improve RC shaping by means of convolution with amplifier
- ✓ Output format mimicks TCT+ data format. Simulation can be analyzed with standard eTCT analysis software
- ☑ Improved performance using less carriers per simulation
- ☐ Further performance improvements through parallelization
- ☐ Fit simulation to experimental data
- ? Irradiated simulation in GUI
- ? Input file to avoid recompiling all the time

Near future

Type of simulation	Before improvements	After Improvements	Expected with parallelization
edge-TCT/50ps 1-laser height	~200s	~20s	3-10s
edge- TCT/50ps/3um full detector	~3h	~30min	4-15min

Simulation time



Trimmed version of *.carriers file

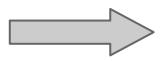
Make "main.cpp" accept input parameters



Will call "main.cpp" with different Neff configurations searching for the best fit to measurements Write minimization code χ^2

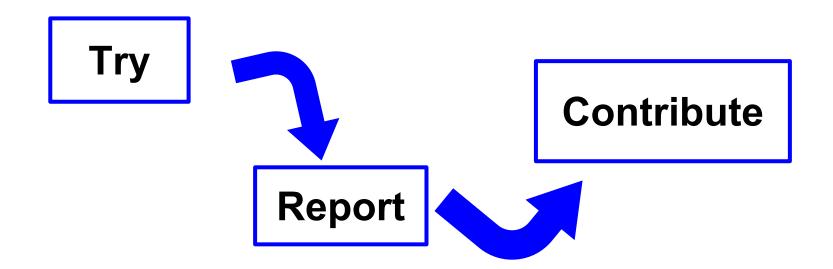
One more thing...

Code is available on GitHub



github.com/IFCA-HEP/TRACS

You are encouraged to



Thanks for your attention

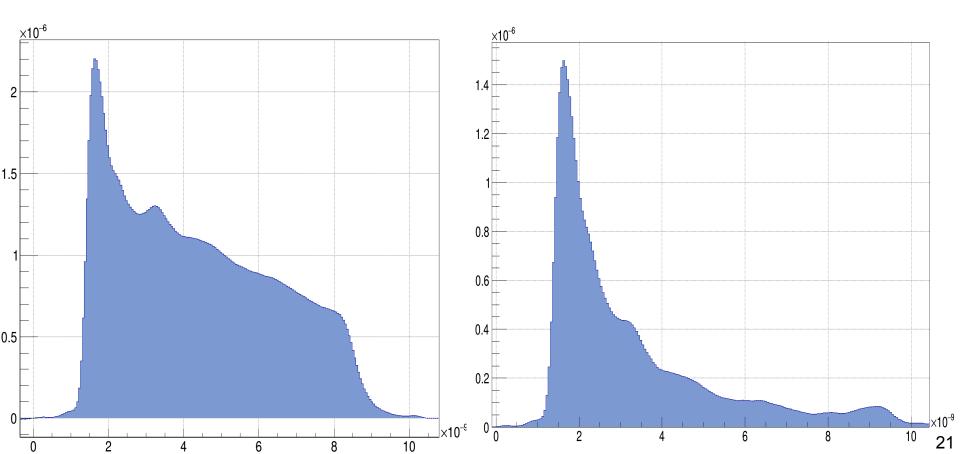
- Microstrip
- IR laser
- edge-TCT (~15μm)

- Bias = 500v
- Vdep* = 250v

*Vdep has no relevance for irradiated simulations

Non-irradiated mirostrip

Irradiated mirostrip



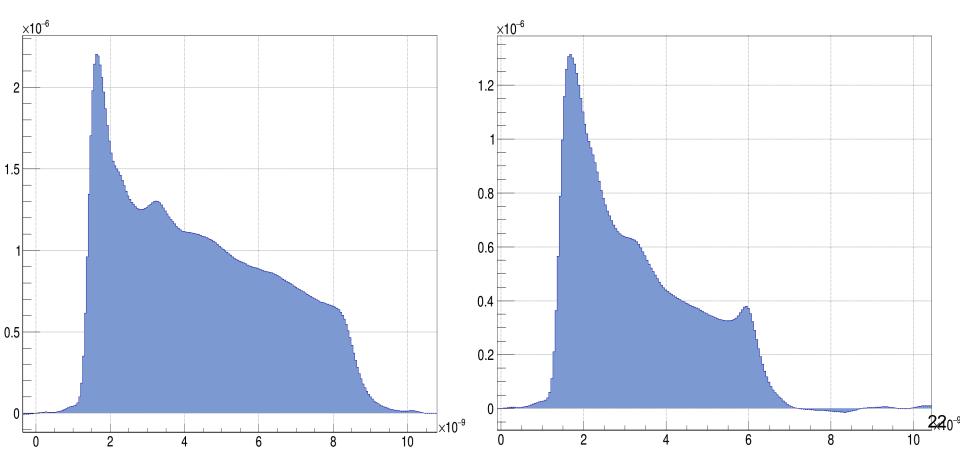
- Microstrip
- IR laser
- edge-TCT (~290µm)

- Bias = 500v
- $Vdep^* = 250v$

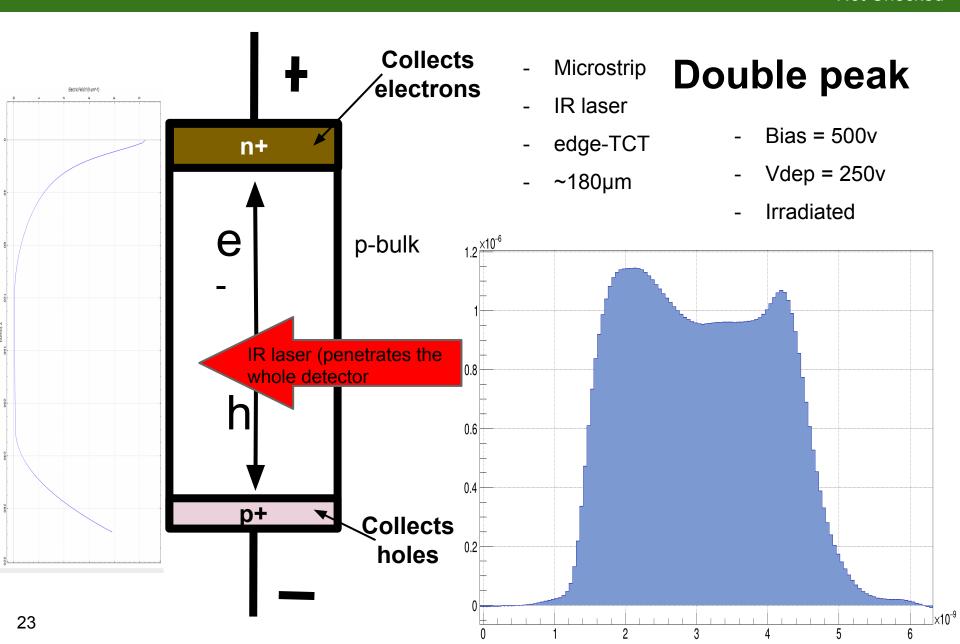
*Vdep has no relevance for irradiated simulations

Non-irradiated mirostrip





Second Approach* - 3 zone Neff



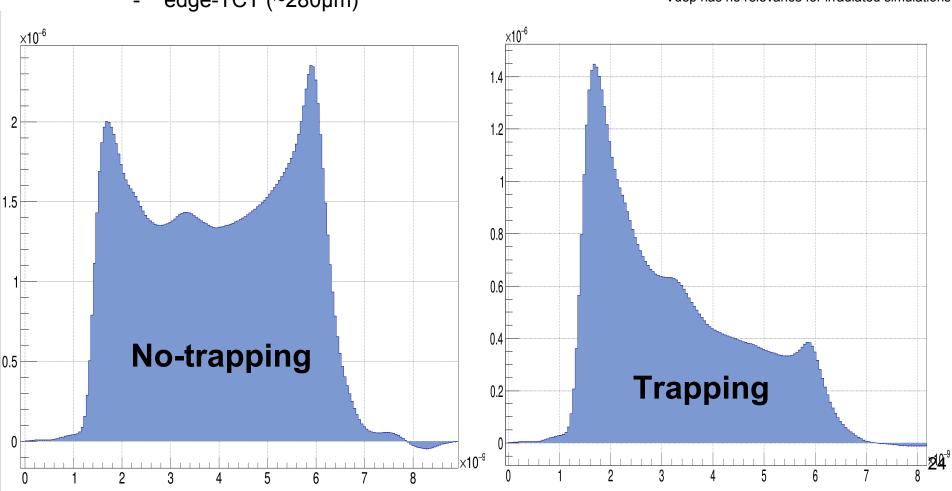
Second Step - Trapping

Simple exponential decay - Fast and accurate enough

- Microstrip
- IR laser
- edge-TCT (~280μm)

- Bias = 500v
- $Vdep^* = 250v$

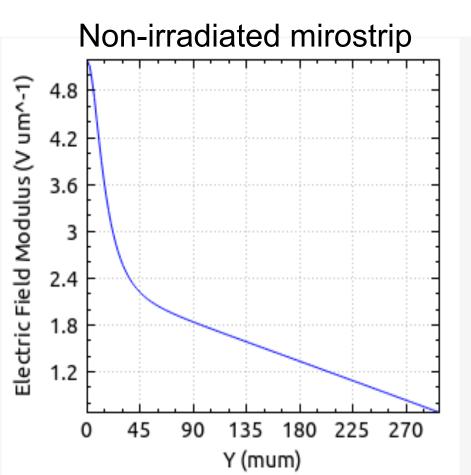
*Vdep has no relevance for irradiated simulations

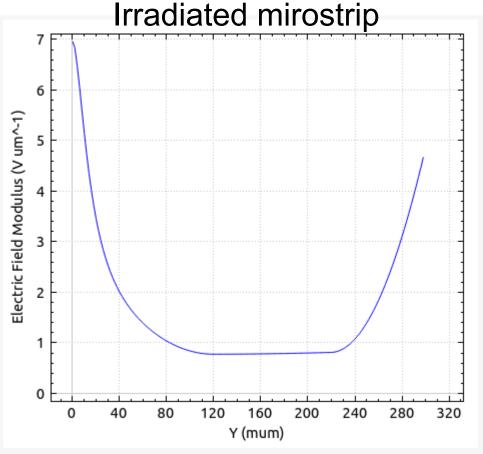


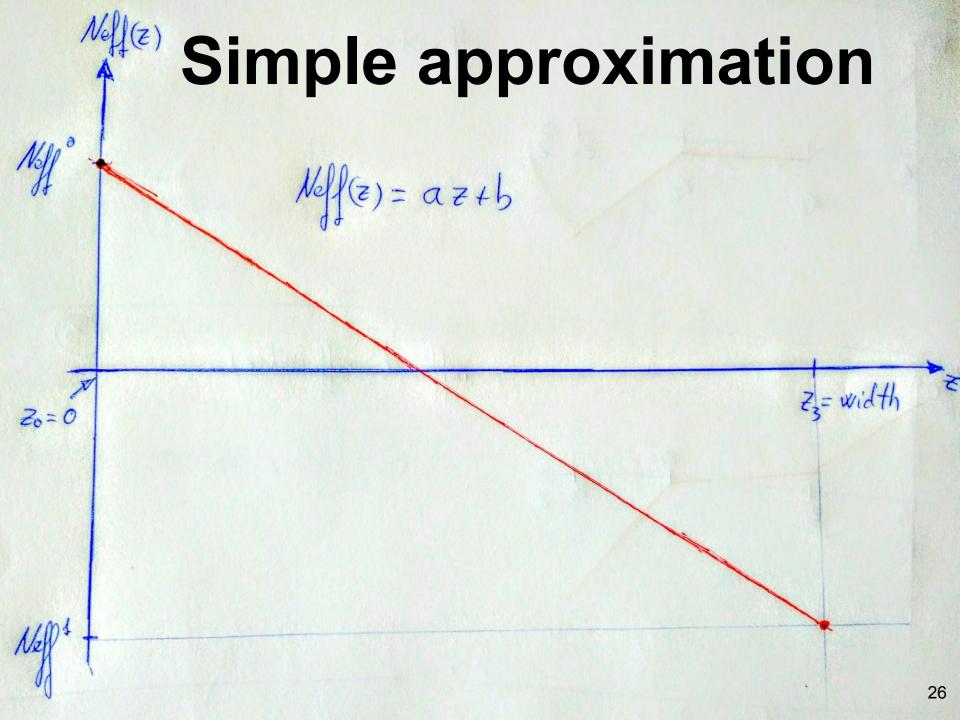
FIELDS

- Microstrip
- Bias = 500v
- $Vdep^* = 250v$

*Vdep has no relevance for irradiated simulations







Agreement with published results

